#### LETTER

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#### Fast and high light yield scintillation in the Ga<sub>2</sub>O<sub>3</sub> semiconductor material

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We report the distinct scintillation properties of the well-known  $Ga_2O_3$  semiconductor material. Under UV excitation, the photoluminescence (PL) emission peak appeared near a wavelength of 380 nm with a quantum yield of 6%, and fast decays of 8 and 793 ns were observed. In contrast, the X-ray-induced scintillation spectrum showed an intense emission band near a wavelength of 380 nm, whose decay curve was reproduced using two exponential decay components with time constants of 8 and 977 ns. The pulse height spectrum of <sup>137</sup>Cs  $\gamma$ -rays measured using Ga<sub>2</sub>O<sub>3</sub> showed a clear photoabsorption peak with a light yield of 15000 ± 1500 photons/MeV. © 2016 The Japan Society of Applied Physics

adiation detectors have been utilized in many kinds of nondestructive investigations. In many such applications, a scintillation detector, which consists of a scintillator and a photodetector, is used. A scintillator is a type of a luminescent material that converts a high-energy ionizing radiation (photon or particle) to hundreds of visible photons via energy migration from the host matrix to the emission centers.<sup>1)</sup> Scintillators play an important role in many scientific and industrial fields, including astrophysics,<sup>2)</sup> particle physics,<sup>3)</sup> medical imaging,<sup>4)</sup> security,<sup>5)</sup> nuclear plants,<sup>6)</sup> and well-logging.<sup>7)</sup> In general, scintillation detectors can be classified into two types. The first type is based on the photon counting technique, which allows highly sensitive detection and the capability to resolve the radiation energy spectra using pulse height spectroscopy (PHS). The photon counting technique is generally used in high-energy physics industries. The second type is based on signal integration, which has the advantage of fast and high signal-to-nose measurements as long as the incident radiation is intense enough. This technique is mainly used in radiation imaging applications such as applications for airport security and medical imaging.

The scintillation process mainly involves two separate effects. The first effect is absorption of incident ionizing radiation, and another effect is emission of light. Therefore, typical scintillator materials are composed as a host matrix to absorb the radiation energy effectively and emission centers to emit light as scintillation. Nowadays, insulator materials doped using rare earth or transition metal ions are commonly used in practical applications.<sup>8–12)</sup> On the other hand, semiconductor crystals have also attracted attention due to their intrinsically high light yield and fast decay time without doping any emission centers.<sup>13)</sup> As semiconductor scintillators, several materials have been introduced such as Gadoped ZnO, In-doped CdS, CuI, PbI<sub>2</sub>, and HgI<sub>2</sub>.<sup>13,14)</sup> Among these materials, CuI, PbI<sub>2</sub>, and HgI<sub>2</sub> are not used in practical applications since they can only be operated at low temperatures. So far, in terms of practical applications, we have investigated GaN,<sup>15)</sup> ZnO,<sup>16)</sup> and CdS,<sup>17)</sup> and they are found to exhibit fast scintillation due to exciton emission. Particularly, ZnO has a great potential for practical use, and we have developed a photon counting-based two-dimensional imager using ZnO for monitoring charged particles.<sup>18)</sup> Furthermore, throughout the course of research, we noticed that In- and Ga-doped ZnO show an efficient scintillation response characterized by a high light yield and a fast decay time.<sup>19)</sup> Despite these advantages of ZnO, one of the drawbacks is that the fabrication of a bulk form with high density and homogeneity is challenging. Since most radiation types, such as X-rays and  $\gamma$ -rays, have a high penetrating power, these properties are essential for an efficient scintillator material to absorb the radiation energy effectively.

 $\beta$ -Ga<sub>2</sub>O<sub>3</sub> semiconductor crystals are of our great interest to extend our knowledge and to discover new options of semiconductor scintillators.  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> is a recently developed and well-known semiconductor material.<sup>20–26)</sup> It has a relatively wide bandgap of 4.9 eV and a monoclinic structure with C2/*m* space group containing both octahedral and tetrahedral cation sites in equal quantities.<sup>20)</sup> A  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> crystal can be fabricated with a large size and a single crystalline form using a meltgrowth method. Typical applications of Ga<sub>2</sub>O<sub>3</sub> are semiconductor photodetectors,<sup>21)</sup> field-effect transistors (FETs),<sup>22)</sup> and transparent electrodes.<sup>23)</sup> In this study, we investigated the scintillation properties of a  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> crystal since no reports were found on the scintillation responses of this material.

The Ga<sub>2</sub>O<sub>3</sub> sample used in this study is a product of TAMURA, with a size of  $10 \times 15 \times 0.65 \text{ mm}^3$ . Throughout the course of research, the photoluminescence (PL), scintillation, and thermally stimulated luminescence (TSL) properties were comprehensively studied. The PL excitation-emission contour plot was measured using Hamamatsu Quantaurus-OY over the excitation wavelength range of 250-400 nm with an interval of 10 nm. The PL quantum efficiency was also measured using the same instrument. The PL decay time profile was measured using Hamamatsu Quantaurus- $\tau$ . The emission at a wavelength of 380 nm was measured under an excitation wavelength of 280 nm. The X-ray-induced scintillation spectrum was observed using our original setup. The excitation source was an X-ray generator supplied with a voltage of 80 kV and a tube current of 2.5 mA. Detailed information about the setup can be found elsewhere.<sup>27)</sup> The scintillation decay time profile was measured using an afterglow characterization system,<sup>28)</sup> which was equipped with a pulsed X-ray tube. The system integrates the emission signal over the wavelength range of approximately 160-650 nm. The obtained decay profile was approximated using a second-order exponential decay function, from which the two decay time constants were derived. PHS was implemented using a <sup>137</sup>Cs source and a photomultiplier tube (PMT; Hamamatsu R7600U-200). The detailed setup is explained elsewhere.<sup>29)</sup> Here, the absolute light yield was calibrated using Pr-doped LuAG as a standard sample since it showed a scintillation wavelength range of 310-400 nm, which is similar to that of Ga<sub>2</sub>O<sub>3</sub>.<sup>30)</sup> The absolute light yield of the







**Fig. 1.** Excitation (vertical axis) and emission (horizontal axis) map of Ga<sub>2</sub>O<sub>3</sub>.



Fig. 2. PL decay time profile of  $Ga_2O_3$  monitoring at a wavelength of 380 nm under an excitation wavelength of 280 nm.

latter material was previously accurately measured using an avalanche photodiode and a  $^{55}\text{Fe}$  source.  $^{30)}$  The TSL glow curve was measured using Nanogray TL2000 with a heating rate of  $1\,^\circ\text{C/s}.^{31)}$ 

The PL excitation-emission contour plot is shown in Fig. 1. The PL emission was observed near a wavelength of 380 nm under the excitation wavelength range of 260-280 nm. The PL quantum yield was approximately 6%. In pioneering studies, the emission origin has already been well discussed. The emission band is mainly composed of two peaks in the UV and blue ranges. The origin of the UV emission was considered to be the recombination of free electrons and self-trapped holes.<sup>32)</sup> On the other hand, the donor-acceptor recombination involving an oxygen vacancy, interstitial Ga, and Ga vacancies is considered to be the origin of the blue emission.<sup>33,34)</sup> In our sample, the dominant emission was in the near UV region, and the blue emission was not clearly observed. Possibly, the blue emission was still present, but it overlapped with the tail of the UV emission band. Figure 2 shows the PL decay time profile of Ga<sub>2</sub>O<sub>3</sub>. The deduced decay times were 8 and 793 ns. This result is roughly consistent with the previously reported values, which are less than 30 ns with an afterglow on the order of hundreds of nanoseconds for the UV emission<sup>35)</sup> and on the order of microseconds to milliseconds for the blue emission.<sup>20,33</sup> In our experiment, the latter slow emission component was not observed.



Fig. 3. X-ray-induced scintillation spectrum of Ga<sub>2</sub>O<sub>3</sub>.



Fig. 4. X-ray-induced scintillation decay time profile of  $Ga_2O_3$ . The inset expands the time range to  $10\,\mu s$  to show the slower component.

Figure 3 represents the X-ray induced scintillation spectrum. The peak emission wavelength is approximately the same as that in PL, ~380 nm. The spectral range of this emission is consistent with most conventional PMTs. This is an advantage for practical applications. As far as we are aware, this is one of few scintillation semiconductor materials showing emission in this range besides GaN and ZnO. Figure 4 demonstrates the scintillation decay time profile of Ga<sub>2</sub>O<sub>3</sub>. The decay curve consists of two exponential components with time constants of 8 and 977 ns. The decay time of the faster component is the same as that in PL. Although some semiconductor scintillators show faster scintillation due to free exciton luminescence,<sup>15,16)</sup> it is faster than that of common rare earth doped scintillators such as Ce-doped  $Lu_2SiO_5^{37)}$  and  $Gd_3(Al,Ga)_5O_{12}$ .<sup>27)</sup> In contrast, the slower component is longer than that in PL. This is because PL indicates only the direct excitation and relaxation processes of the emission centers while the scintillation processes include some additional processes since the excitation energy is much larger than PL, and the number of generated charges is much greater.



Fig. 5.  $^{137}\text{Cs}\ \gamma\text{-ray-irradiated}$  pulse height spectrum of Ga2O3 and Pr-doped LuAG.



**Fig. 6.** TSL glow curve of  $Ga_2O_3$  after irradiation with X-rays with a dose of 1 Gy. The background (BGD) signal measured without the sample is superposed.

The <sup>137</sup>Cs 662 keV  $\gamma$ -ray irradiated pulse height spectrum is presented in Fig. 5. Since the spectrum clearly illustrates the photoabsorption peak [~640 channel (ch)] and the Compton edge ( $\sim$ 440 ch), the Ga<sub>2</sub>O<sub>3</sub> semiconductor material can be used for  $\gamma$ -ray measurements based on PHS. Considering the quantum yield of the PMT and the peak channel of Pr-doped LuAG as a standard reference, the scintillation light yield of  $Ga_2O_3$  was deduced to be  $15000 \pm 1500$  photons/MeV. To the best of our knowledge, the clear detection of the photoabsorption peak using semiconductor scintillators is only possible in Te-doped CdS and ZnSe.<sup>36)</sup> Compared to these materials, the light yield of Ga<sub>2</sub>O<sub>3</sub> is superior to that of Te-doped ZnSe and comparable to that of Te-doped CdS. These Te-doped semiconductors are well compatible with photodiodes as their emission wavelengths are in the range of 600-800 nm.<sup>36)</sup> Our Ga<sub>2</sub>O<sub>3</sub> semiconductor scintillator is the best to be used with a PMT and is the only option among the semiconductor scintillators used on the photon counting basis. The scintillation decay time of Ga<sub>2</sub>O<sub>3</sub> is much faster than those of Te-doped CdS and ZnSe.

The TSL glow curve of  $Ga_2O_3$  is shown in Fig. 6. The measured signal is clearly distinguished from the background (BGD) signal. We confirmed that the TSL glow signal occurs at a temperature of approximately 400 °C. TSL is due to the trapping and detrapping processes of ionized charges while they travel in the sample. However, in efficient scintillators, ionized charges do not suffer such trapping processes, so that all the absorbed radiation energy is transferred to the luminescent center and fully converted into luminescence. Therefore, the observation of such notable TSL suggests that it has the potential to improve the scintillation light yield.

In conclusion, the optical, scintillation, and TSL properties of a Ga<sub>2</sub>O<sub>3</sub> crystal were investigated. The emission peak near a wavelength of 380 nm was observed in both PL and scintillation spectra. The observed decay times in PL and scintillation were practically consistent. Through pulse height spectroscopy using a <sup>137</sup>Cs  $\gamma$ -ray source, a clear photoabsorption peak was successfully observed, and the light yield was 15000 ± 1500 photons/MeV. The scintillation decay time was 8 ns, which is the fastest among the semiconductor scintillators available for pulse height measurements using PMTs. The TSL glow curve suggests a possibility of further improvement in the scintillation properties.

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